

X-Rays, Electrons and Lithography: Fundamental Processes in Molecular Radiation Chemistry

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EUV Lithography
and Pattern
Transfer



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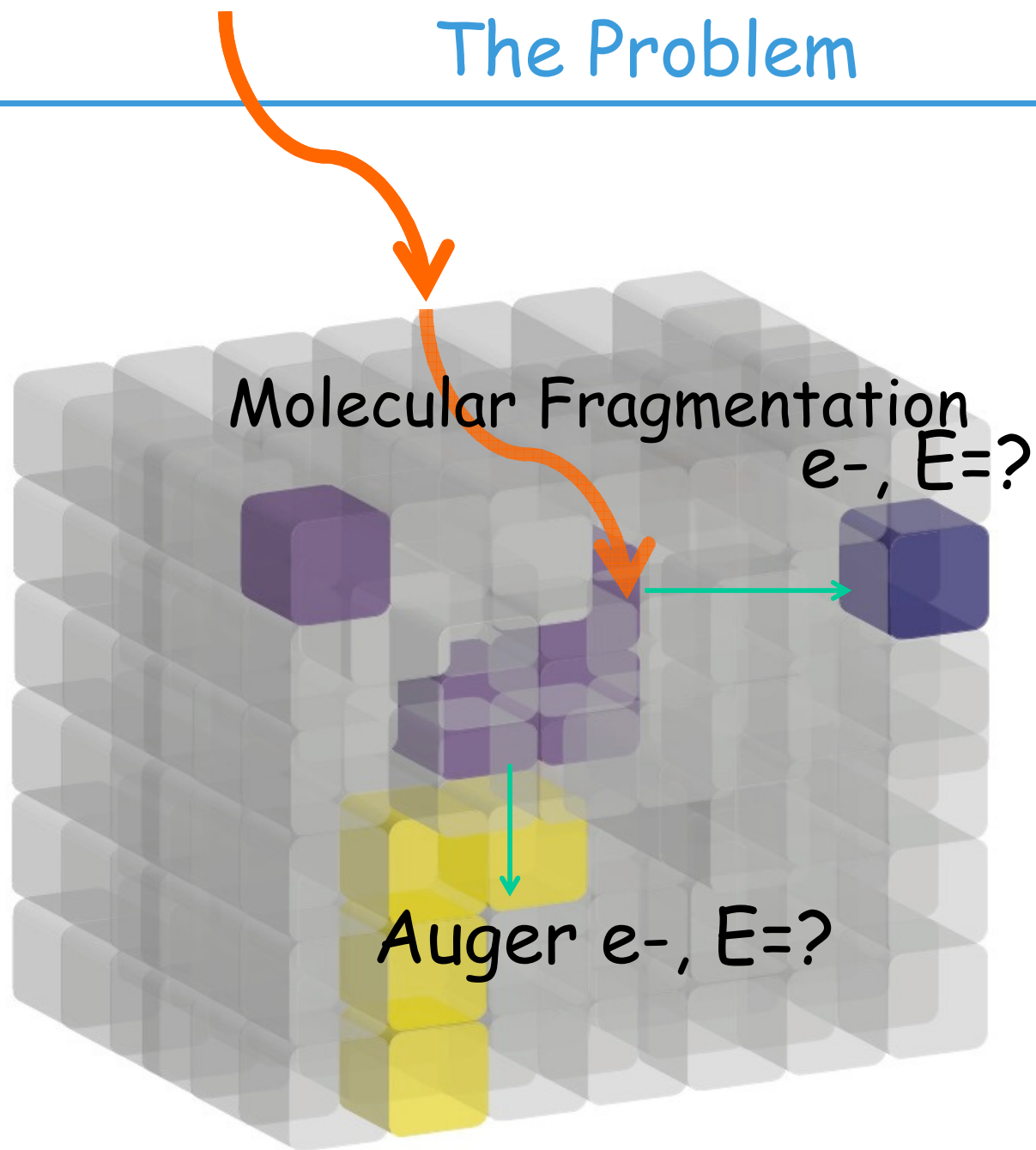
Dan Slaughter Chemical Sciences

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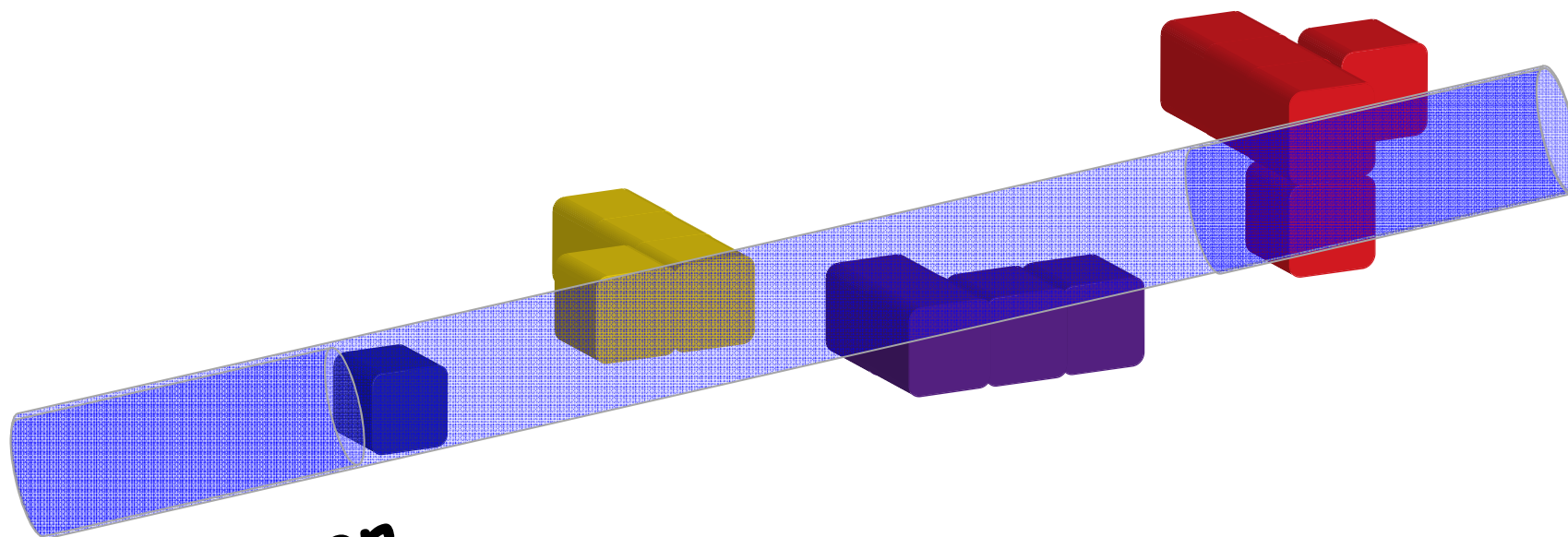


Theory
Kristina Closser, David
Prendergast Foundry

The Problem

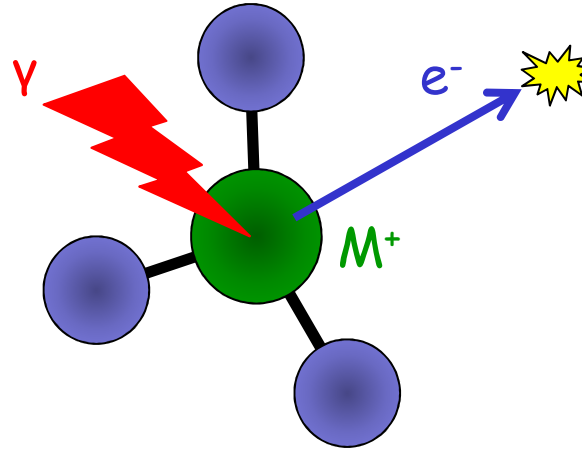
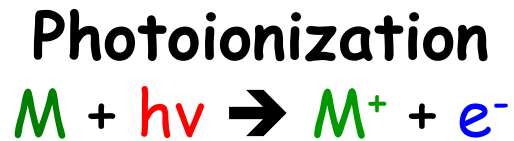


Bulk vs Gas Phase



X-Ray or
e-beam

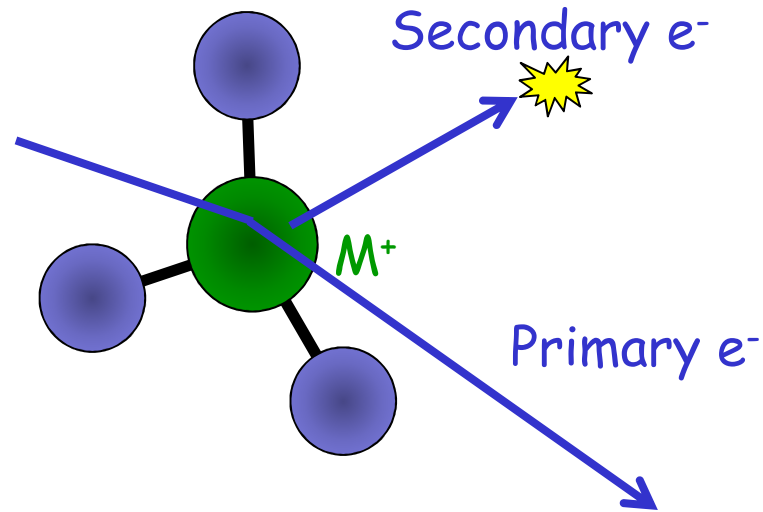
EUV "Standard Model"



92 eV x-ray in
 ionization energy ~ 10 eV
 ~ 80 eV secondary electron out
 Stable parent ion left behind

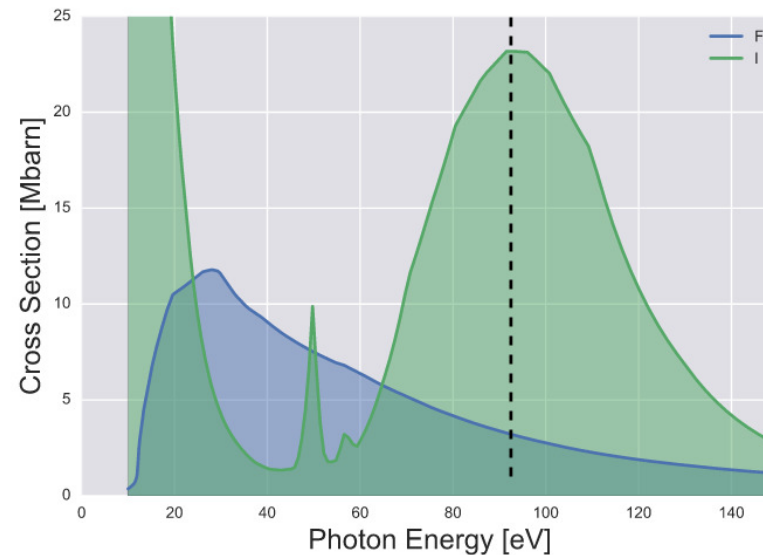
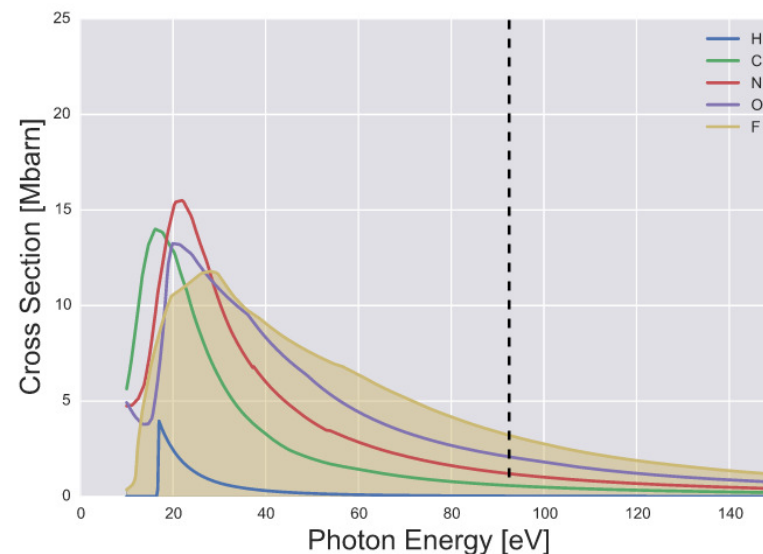
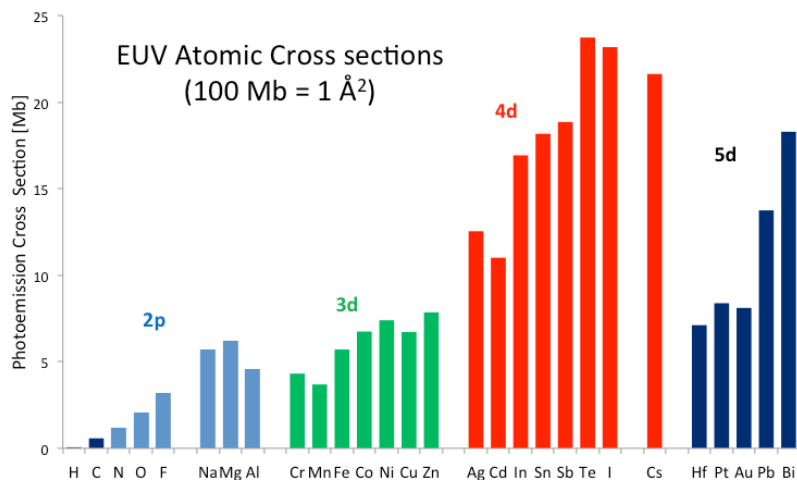
The electron does the work!

Impact Ionization



Fast primary electron in
ionization energy ~ 10 eV
 ~ 10 - 30 eV secondary electron out
 20 - 40 eV energy transfer
Stable parent ion left behind

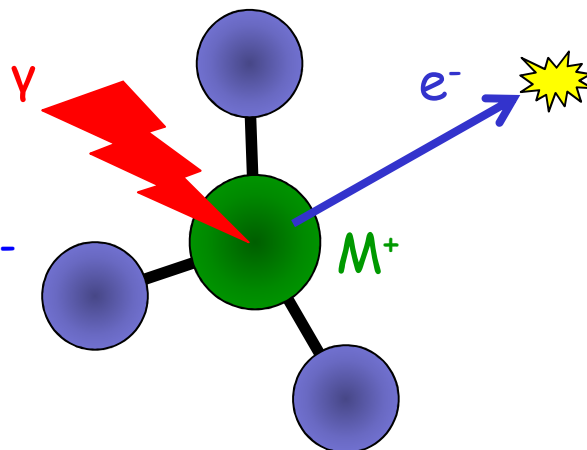
The SE does the work!



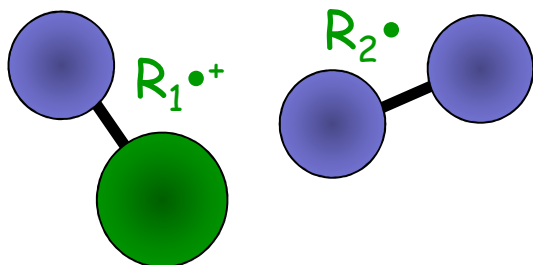
A molecule has *many* cross sections,
one for each orbital
Orbitals closer to the photon energy
have *higher* EUV cross sections
Photoemission from deeper levels
leaves significant *residual energy* in
the ionized molecule

Cross section data cxro.lbl.gov

Step 1 Photoionization

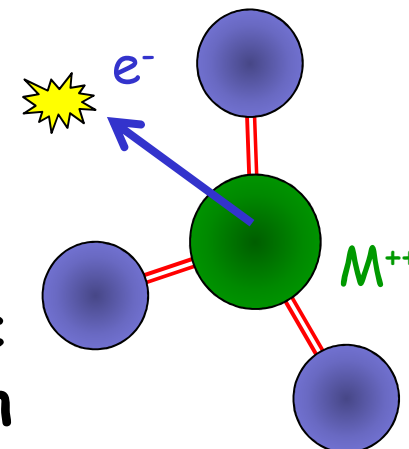


Step 3 Atomic Relaxation Fragmentation?

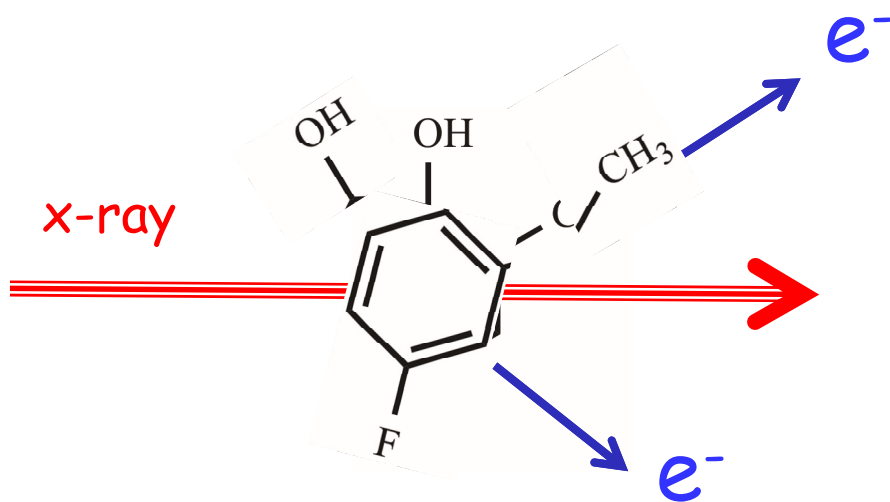


Step 2 Electronic Relaxation

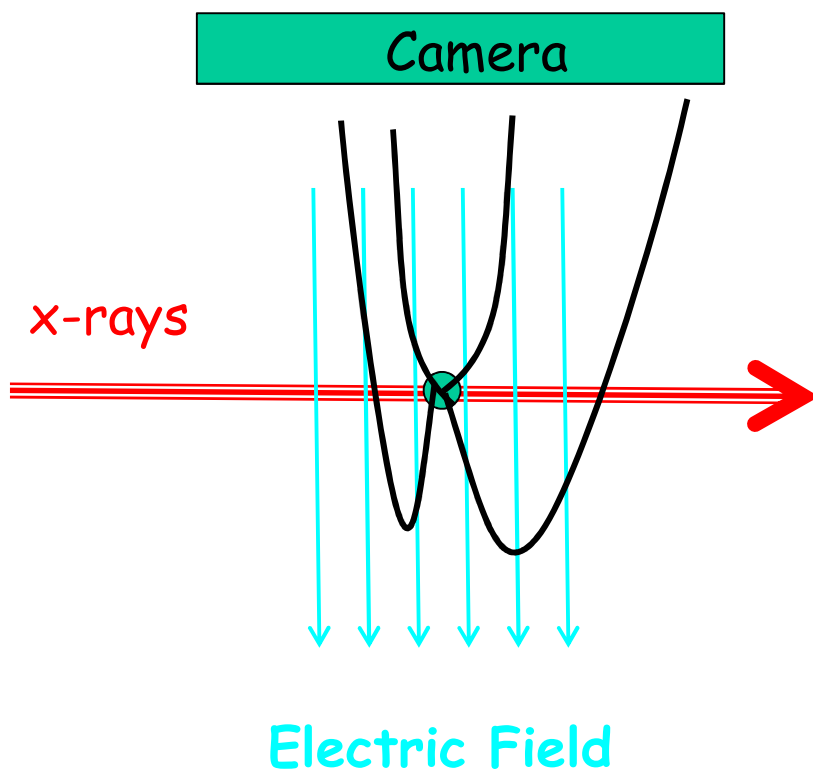
Auger process ?



D. F. Ogletree, *Molecular Excitation and Relaxation of Extreme Ultraviolet Lithography Photoresists*. In Frontiers of Nanoscience: Materials and Processes for Next Generation Lithography, Eds. A. P. G. Robinson and R. A. Lawson, Elsevier 2016



- ◆ Count electrons, energy distribution
- ◆ Count ions and ionized fragments
- ◆ Branching ratios for different processes
- ◆ Cross sections
- ◆ Photon energy dependence

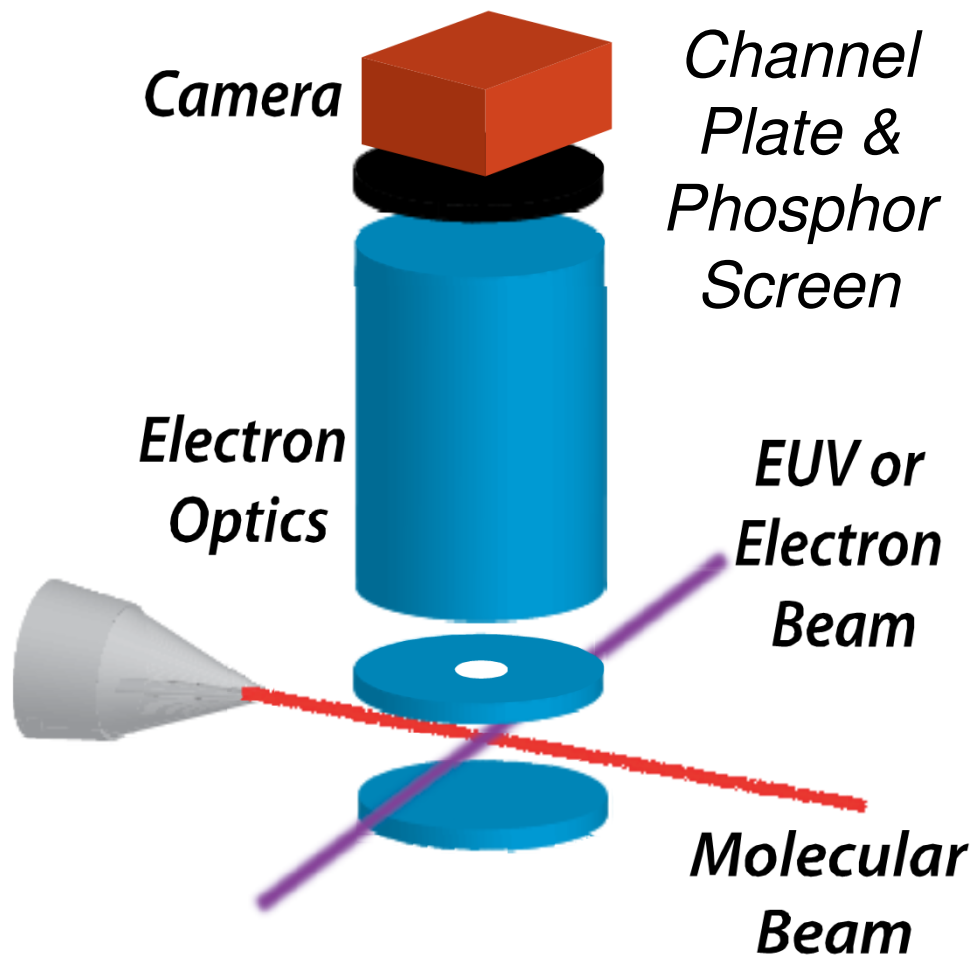


All electrons pushed into imaging detector (4π collection)

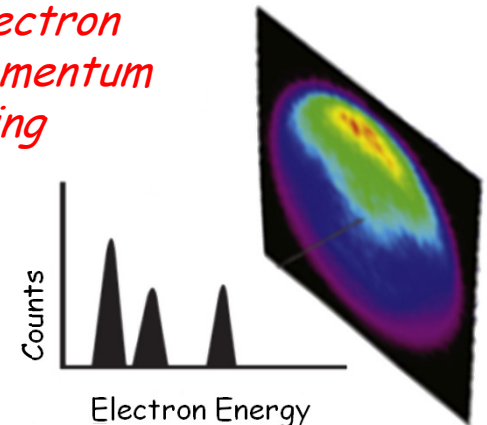
Radial position depends on emission energy and angle

Positive ions detected with reversed field (Time of Flight)

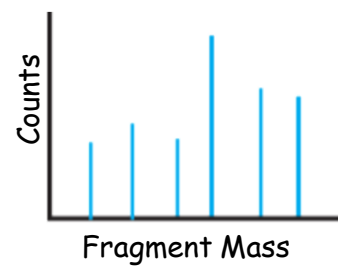
Gas Phase Instrumentation



*Photo-electron
energy-momentum
imaging*

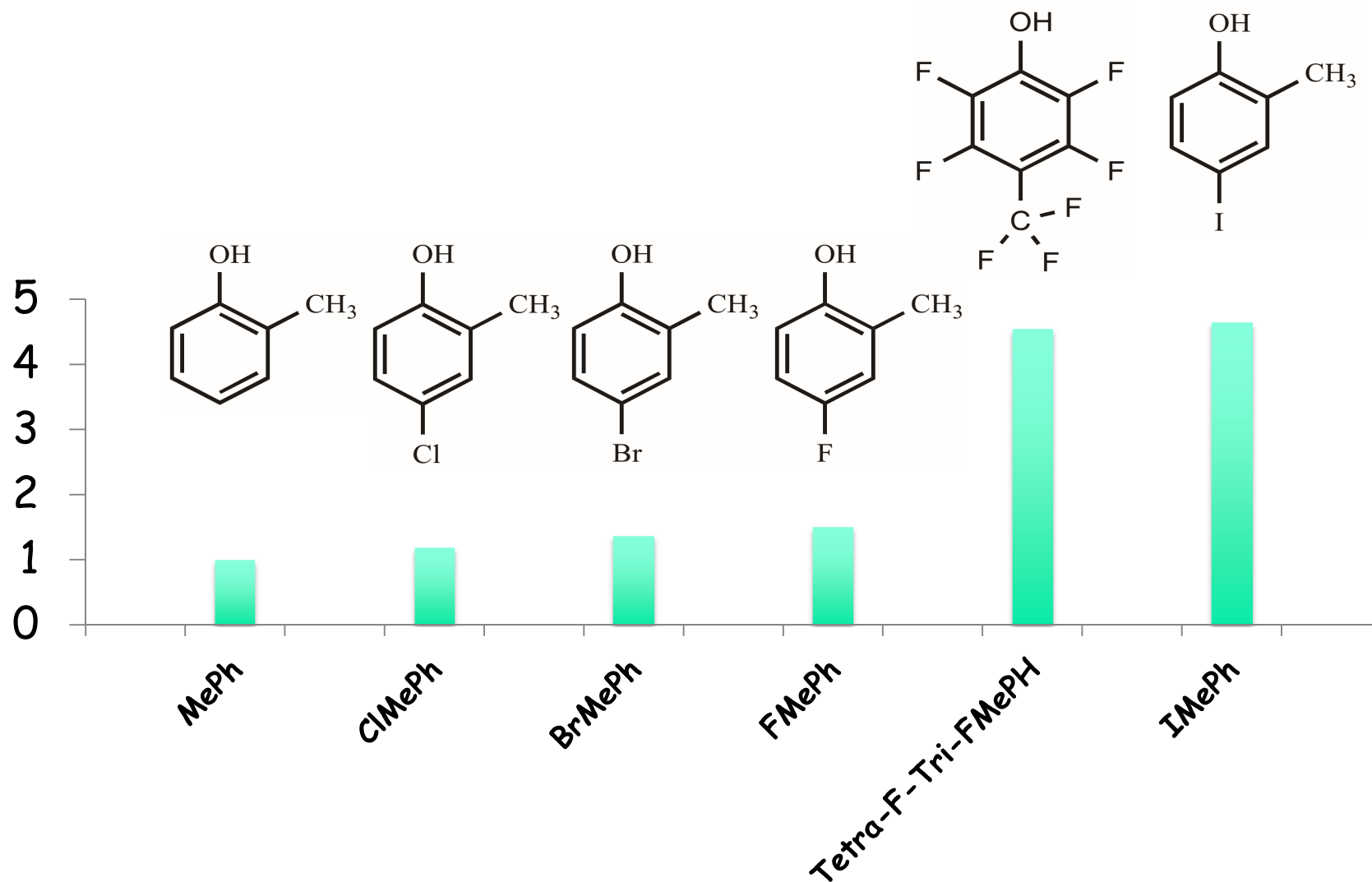


*Time-of-flight
mass
spectroscopy*



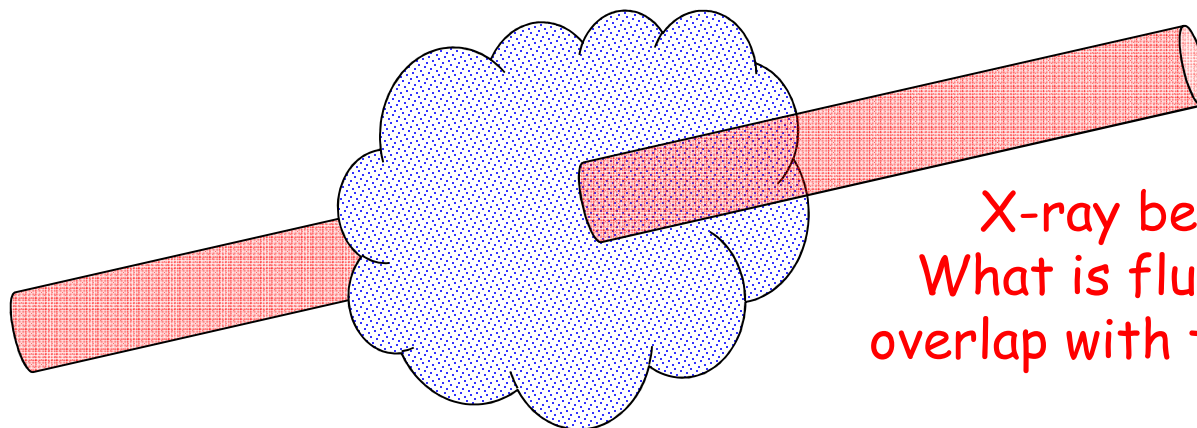
Methylphenol Model Compounds

Relative EUV Cross-Section



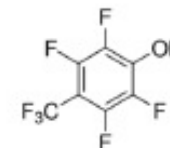
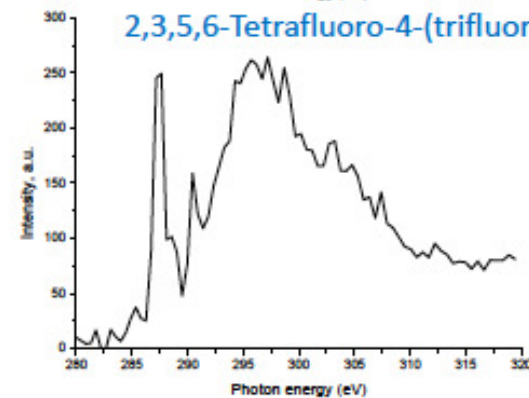
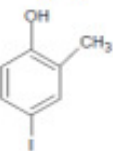
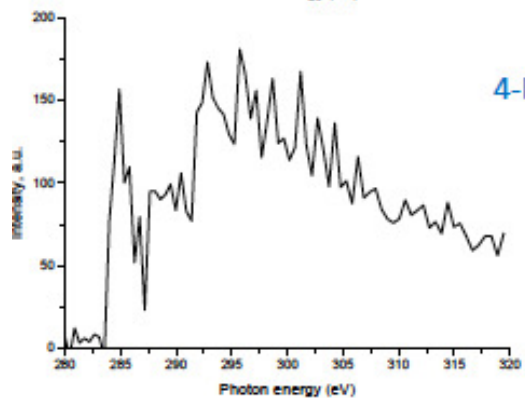
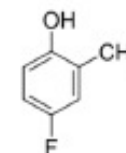
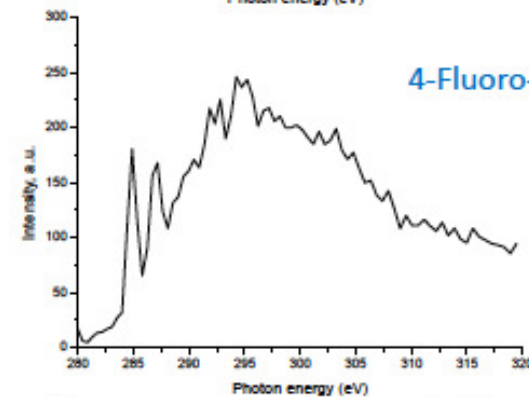
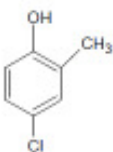
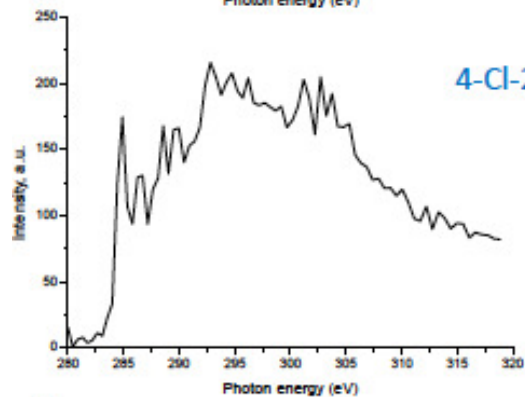
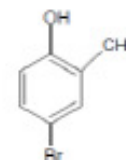
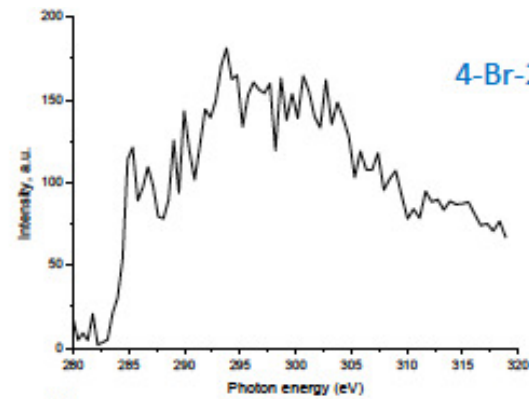
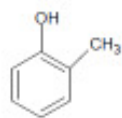
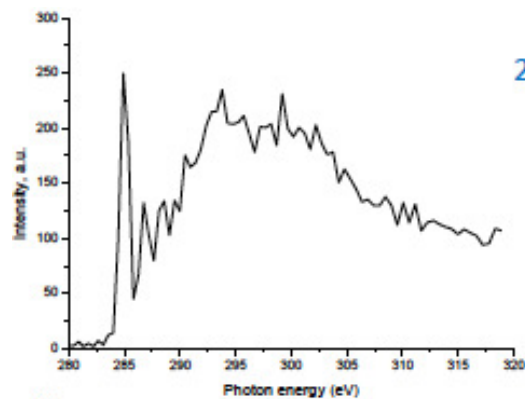
How to Quantify?

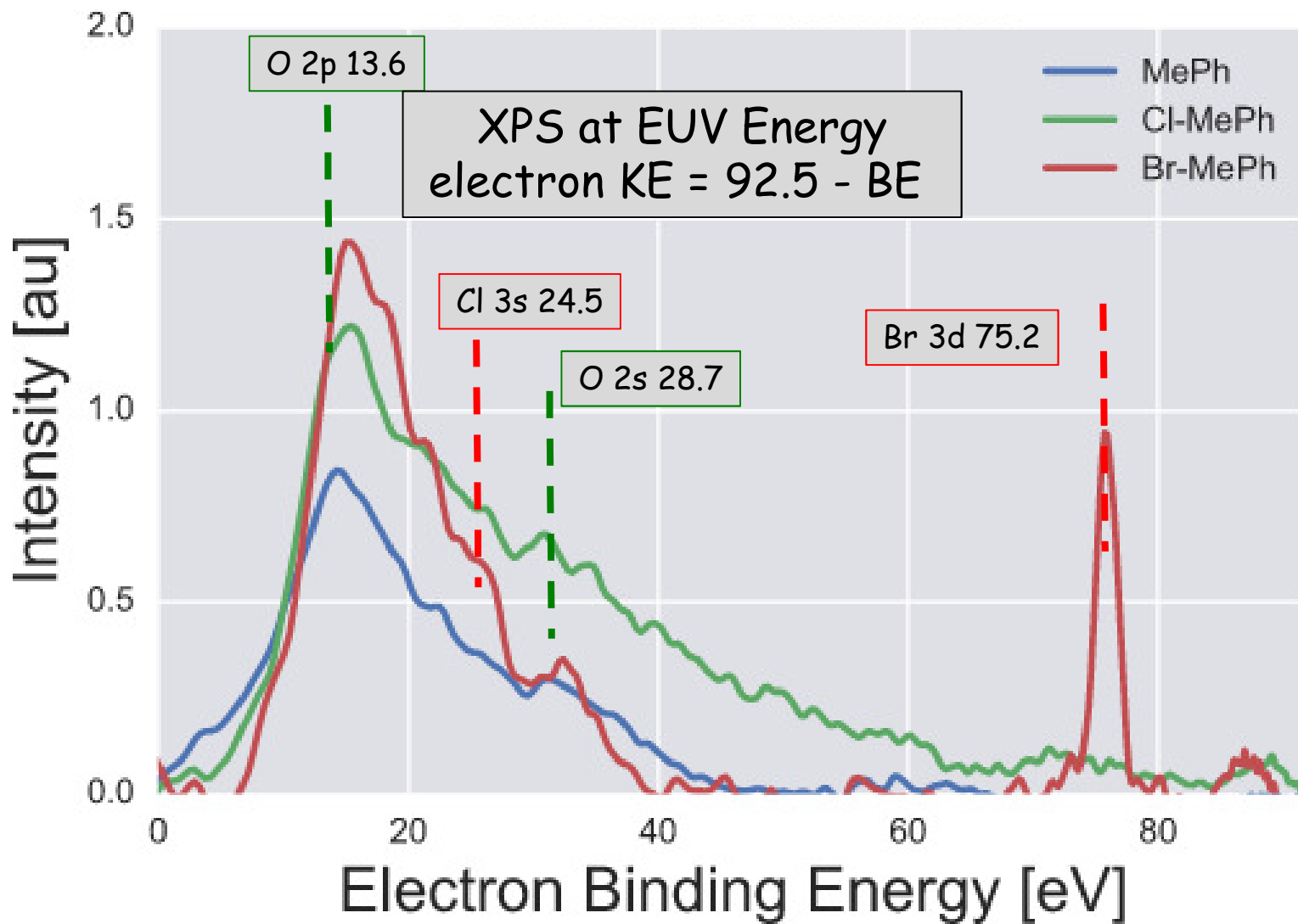
Cloud or molecular beam of gas
What is density and distribution?

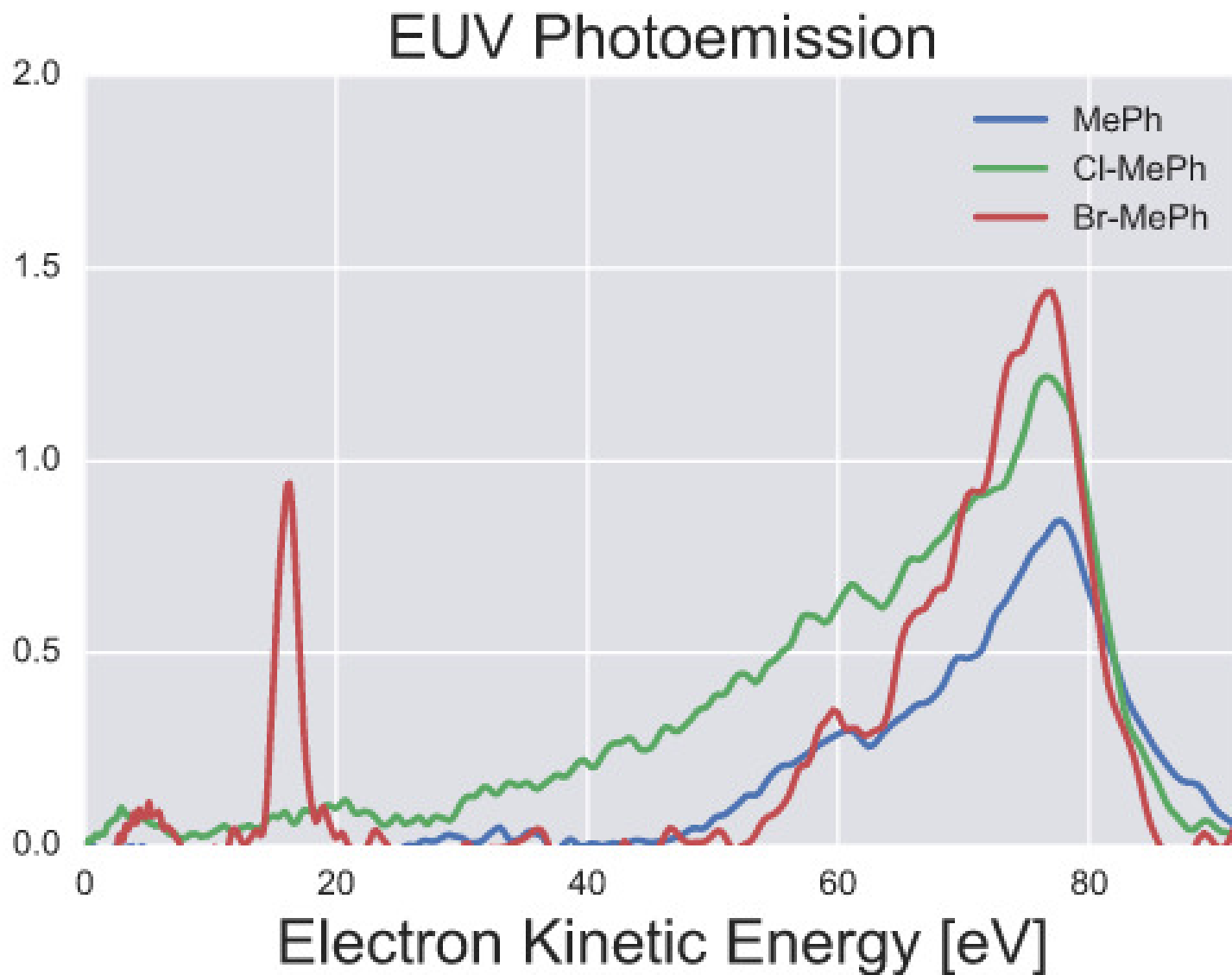


X-ray beam
What is flux and
overlap with target?

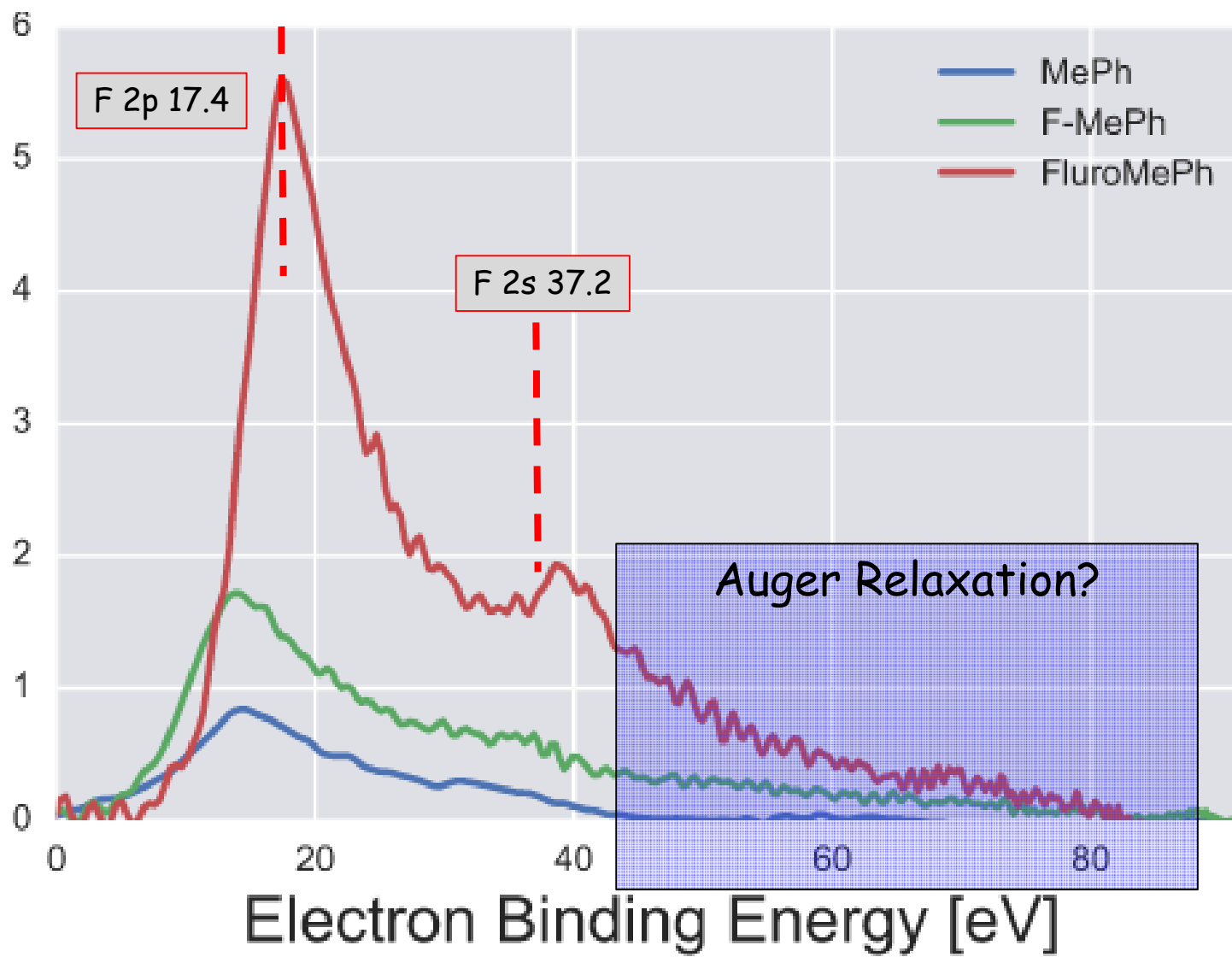
All the molecules have 7 carbon atoms
Scan the photon energy through the carbon 1s
edge (XAS) and measure the ion yield
The "edge jump" ~ 50 eV above threshold is
proportional to the gas pressure
All the photoemission spectra are normalized to
the same number of phenol molecules



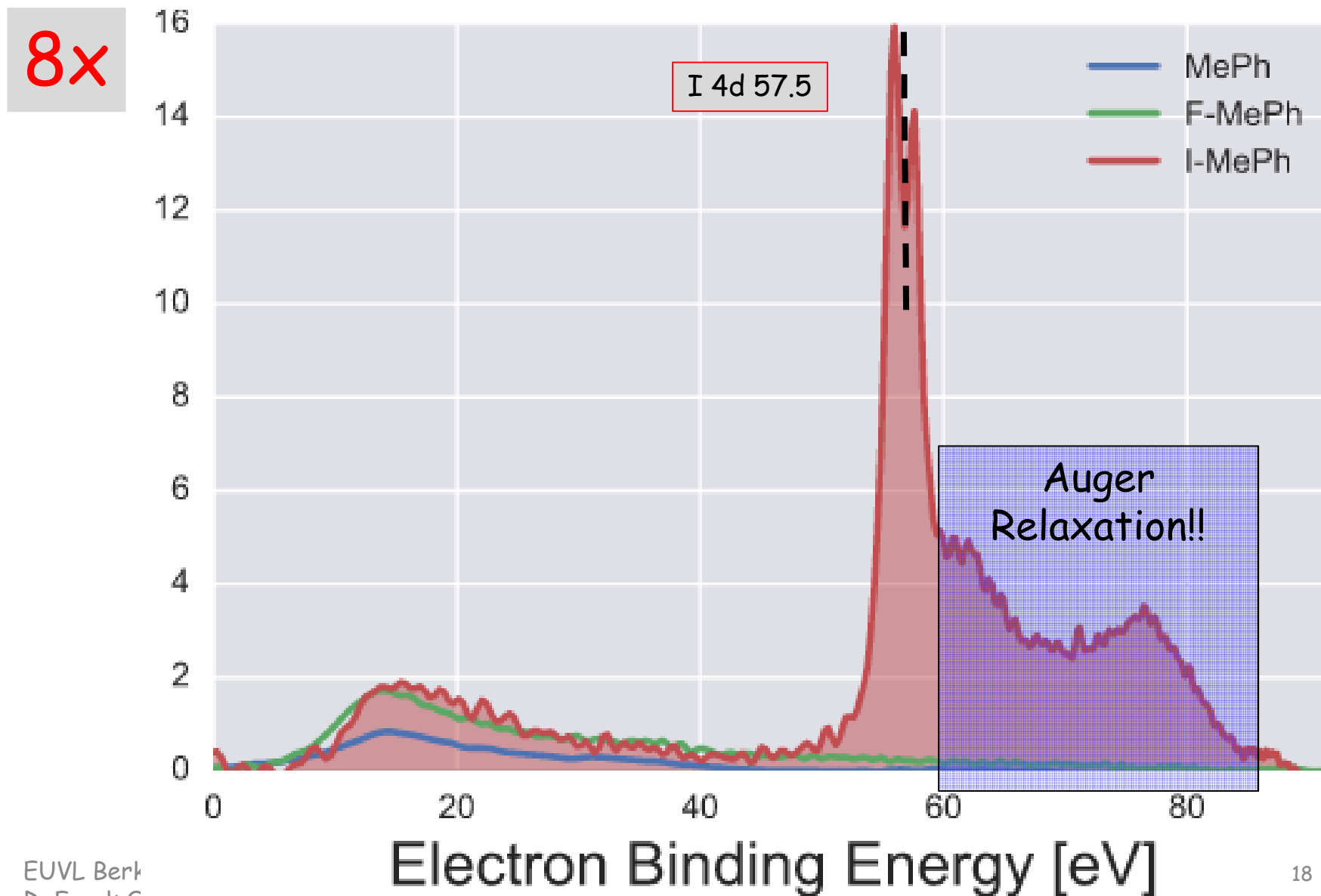


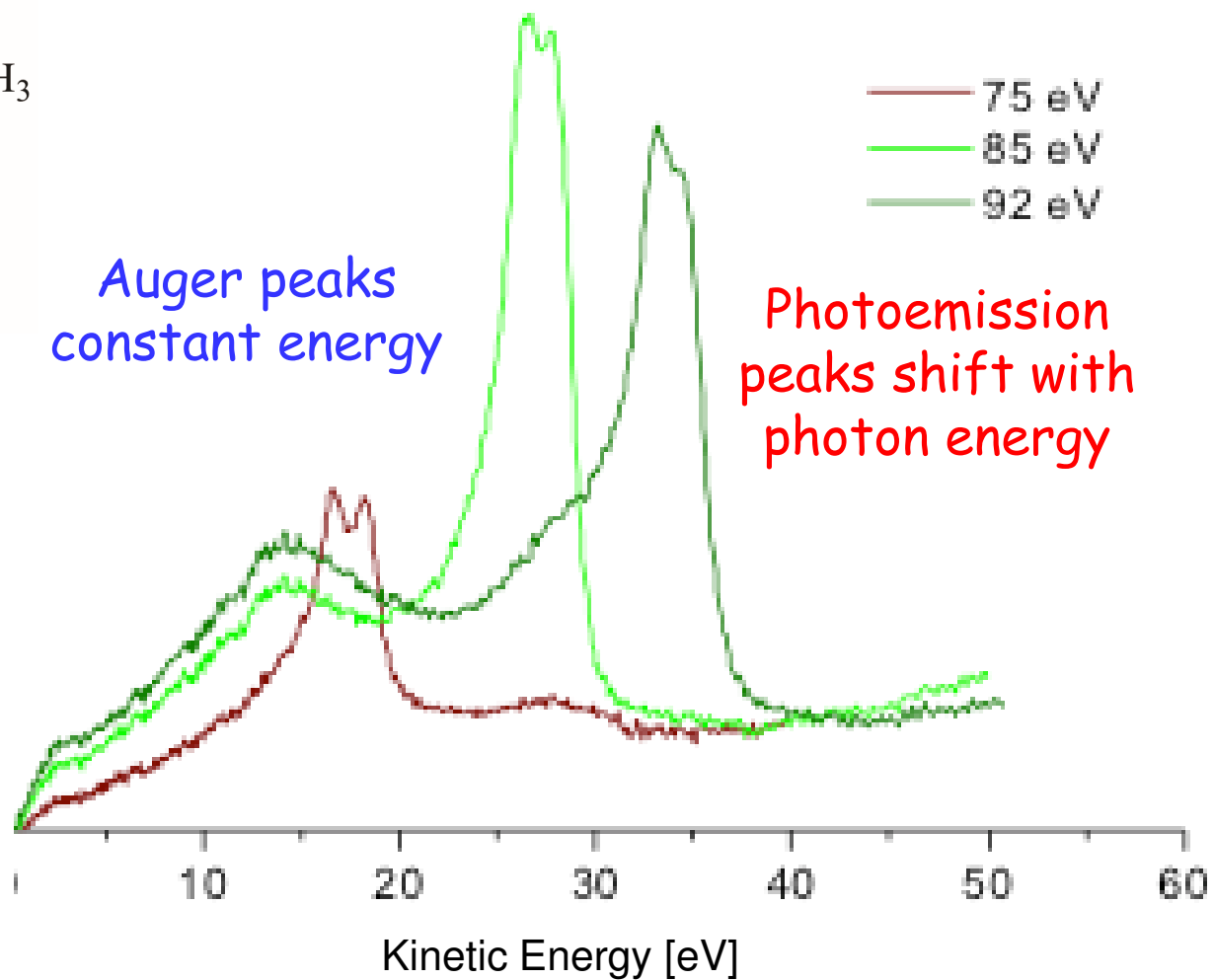
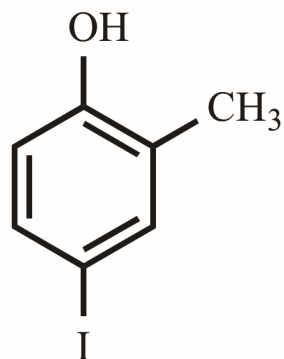


3x

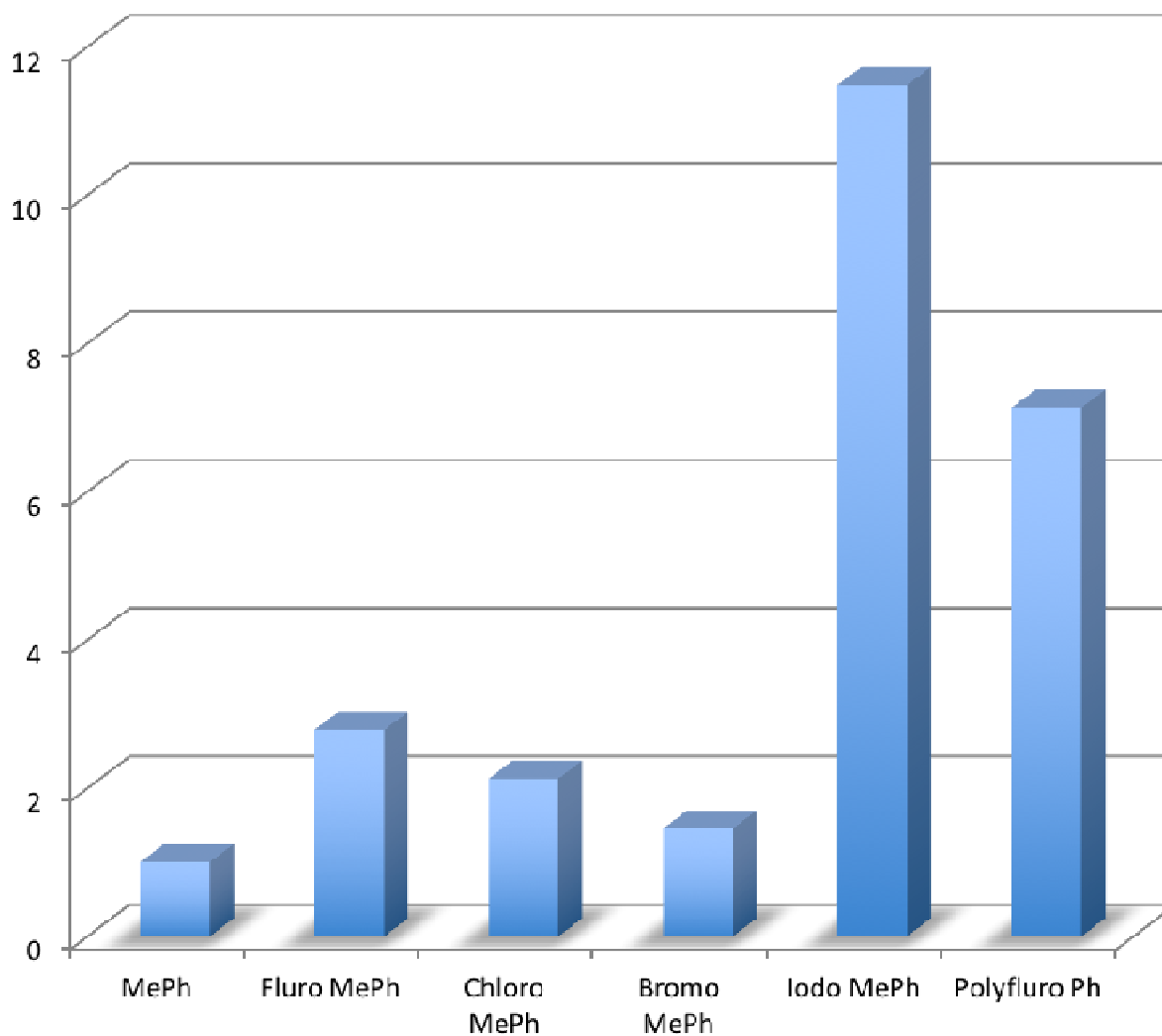


Effects of Iodine





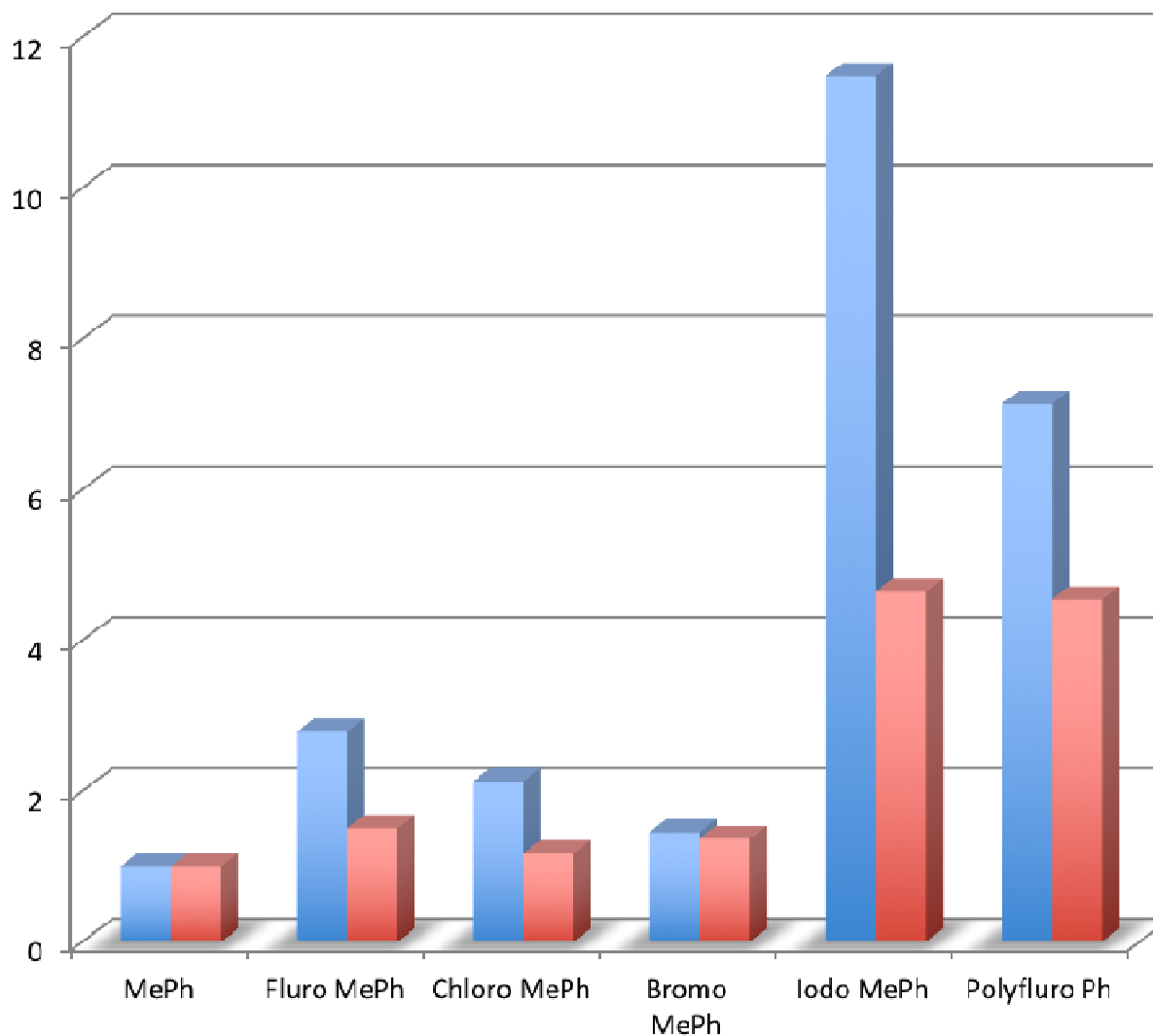
Per-Molecule Electron Yield



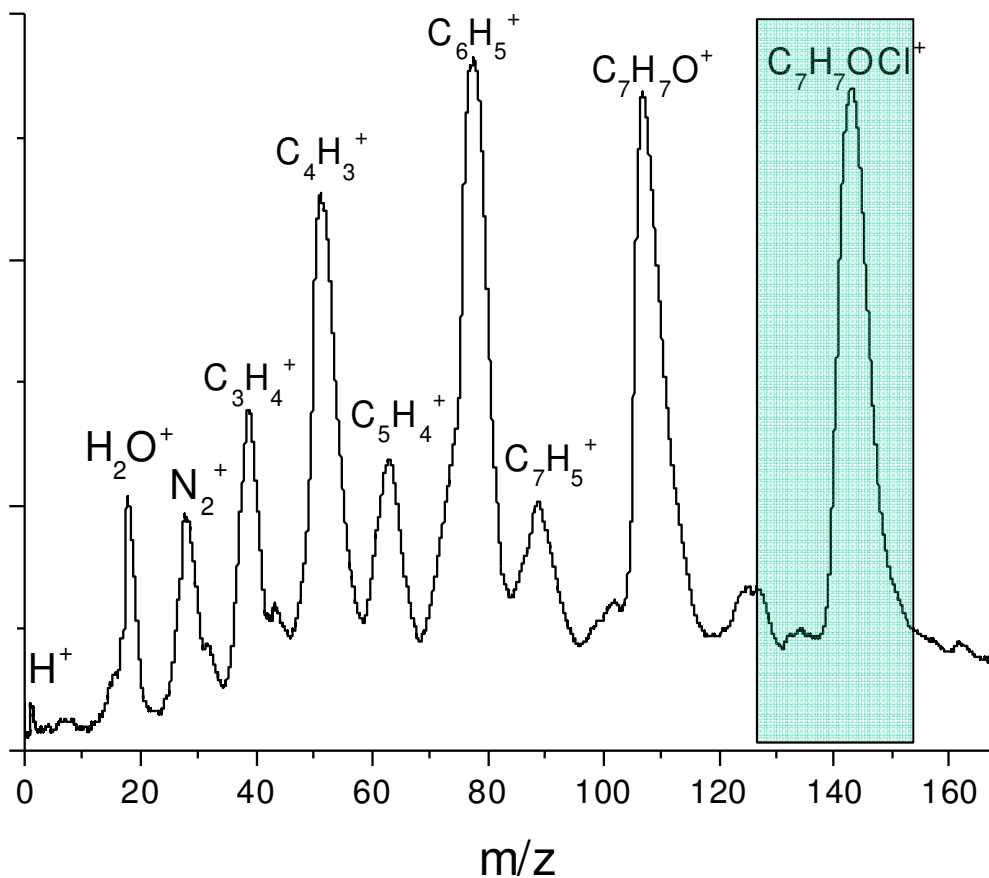
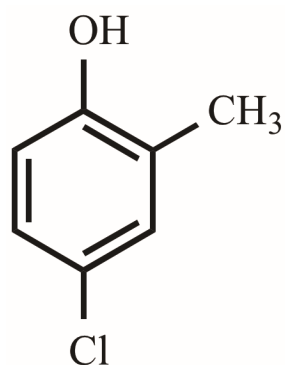
Yield and Cross Section

Cross Section

Electrons

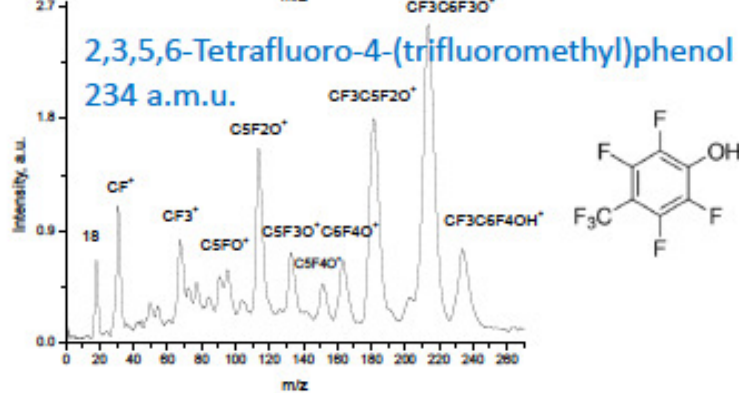
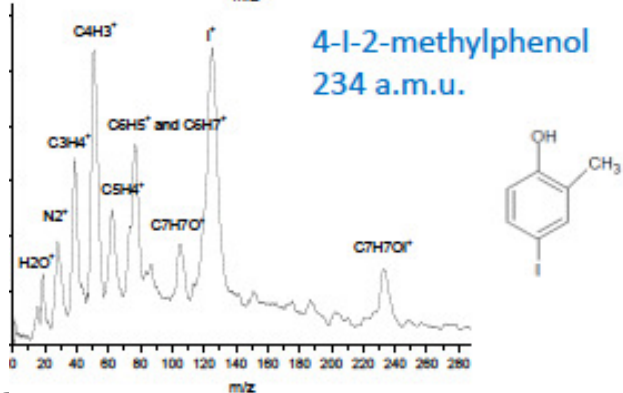
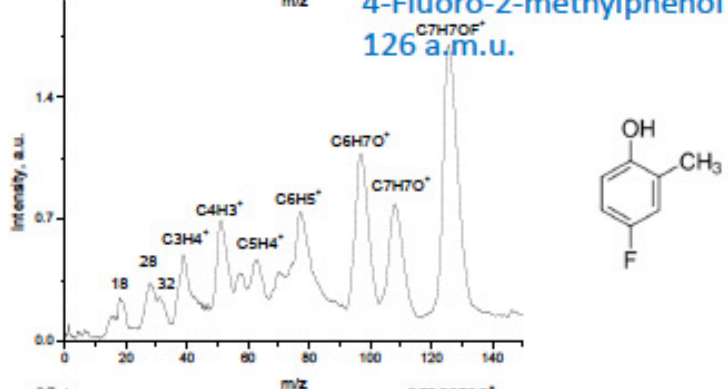
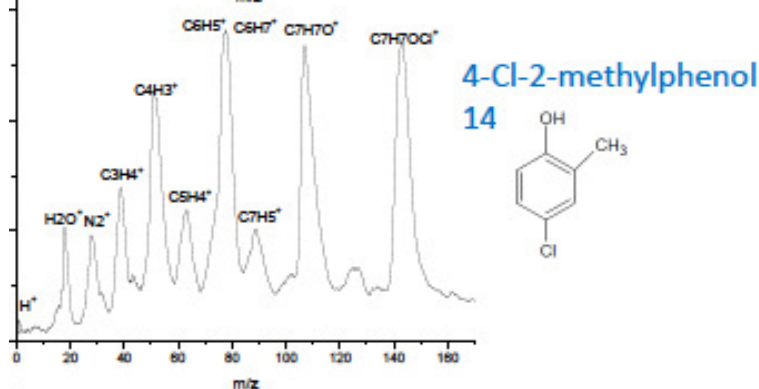
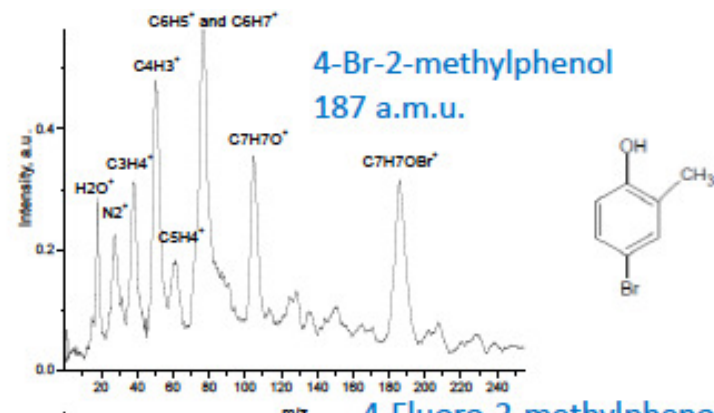
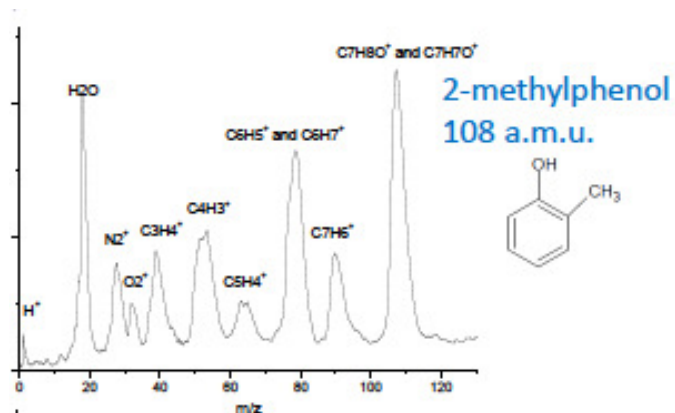


- ◆ Electron yield per molecule can be significantly increased by incorporating high cross-section atoms
 - Iodo-methyl Phenol ~ 10x
 - Fluro-methyl Phenol ~ 1.5 x
- ◆ Photoemission can create more than 2 electrons per molecule through Auger relaxation
 - Energy distribution is changed, can be two ~ 35 eV electrons instead of one ~ 80 eV electron
- ◆ Is this better or worse for pattern transfer ??
 - Better photon statistics
 - Can lower energy SEs reduce electron blur ?
 - Can multiple electrons drive “multi spur” chemistry ??
 - Can resist chemistries be tailored to exploit EUV photoemission?

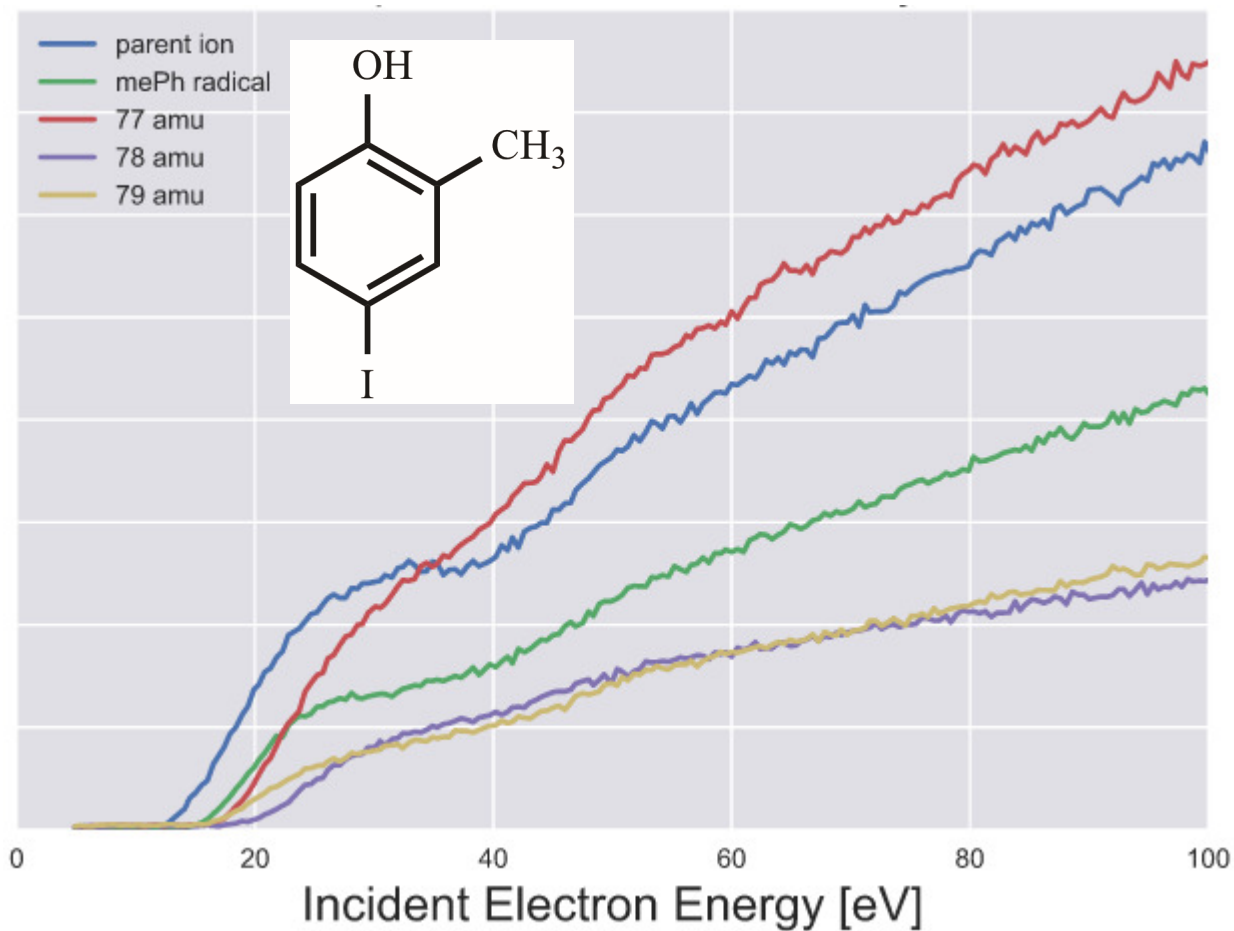


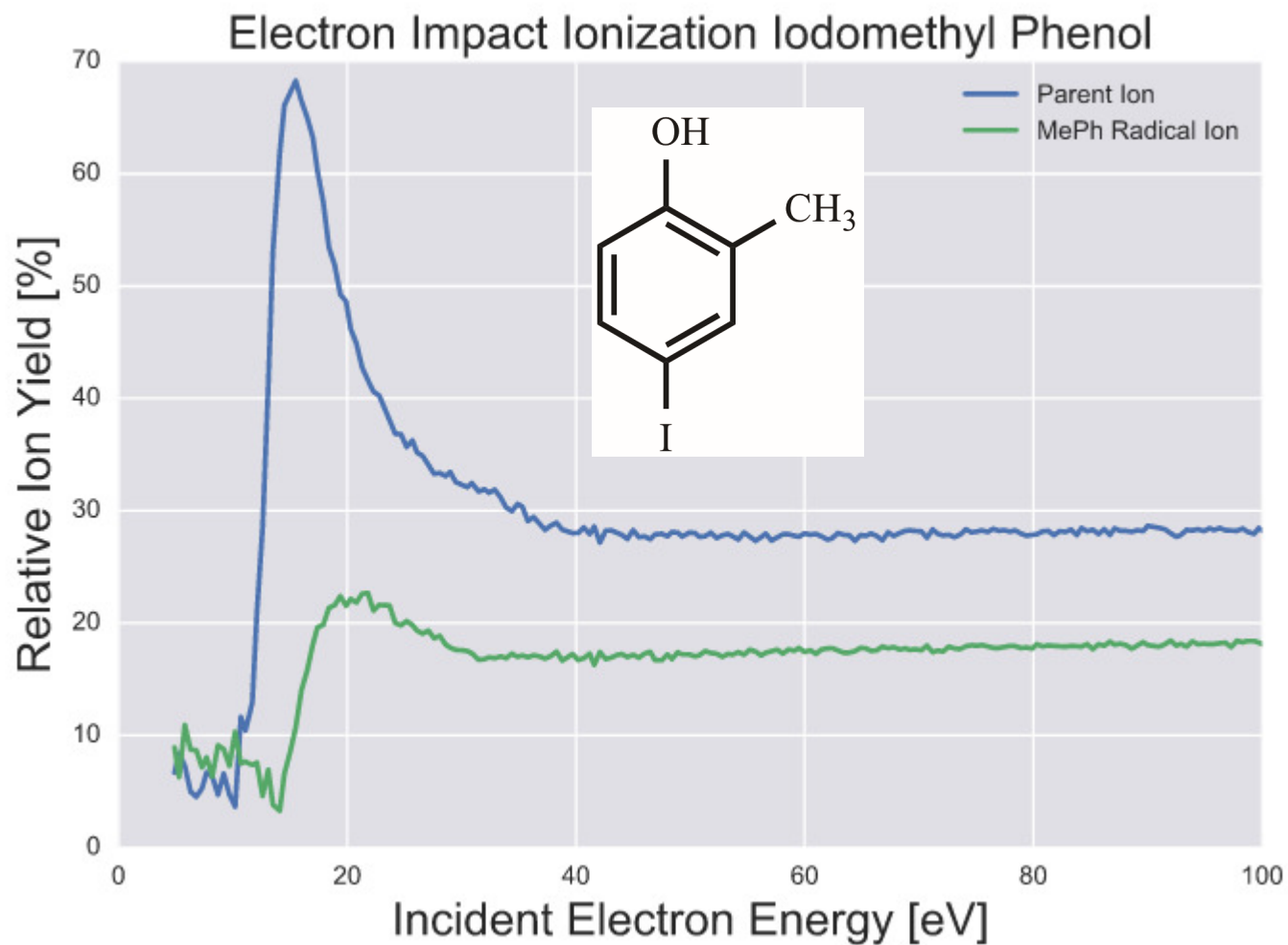
Chloro-Methyl Phenol Fragmentation by EUV photons

EUV Fragmentation Patterns



Electron Impact Ionization





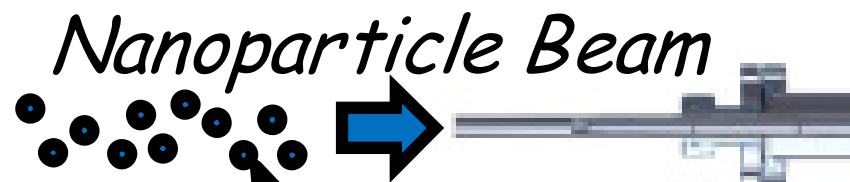
- ◆ EUV photoabsorption fragments molecules
 - Parent ion generation less than ~ 10%
 - Radicals, excited-state ions and small molecules are generated
- ◆ Auger relaxation will always fragment molecules
- ◆ Can Secondary Ions be exploited to drive pattern formation?
- ◆ H^+ can be directly generated in the primary event
 - Should with think about “XAG”, x-ray acid generators?
 - Is there a way to provide solvating anions for acid catalysis?
- ◆ Can the simultaneous, localized generation of electrons and ions be exploited?

Gas Phase Molecules

- ◆ Quantitative photoemission and absorption cross sections for each molecular component
- ◆ Electron yield and energy spectrum, Auger relaxation
- ◆ Ion yield and mass spectrum, fragmentation patterns
- ◆ Variable photon energy photoemission at the synchrotron
- ◆ Electron-molecule interactions, dissociative electron attachment

Condensed Films

- ◆ Molecular structure and bonding almost unchanged
- ◆ Photoemission lines broadened, dielectric film reduces energies ~ 5 eV
- ◆ Film photoemission mixed with inelastic losses, all molecules contribute, only near-surface region detected
- ◆ Reaction cascade, transient electrons/ions/radicals decay or react in fs to ns to us, very hard to detect
- ◆ Some reaction products stable (latent image)

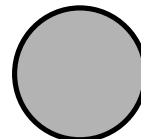


Aerodynamic lens for larger particles

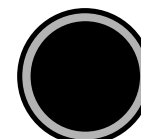
Nebulizer or Electrospray
Ionization for smaller particles
and large molecules

Nanoparticles:

uniform



core-shell



50-500nm



polymer resist
particle

Continuous change from small molecule to
condensed phase, add complexity
Damage free characterization with
molecular or aerodynamic beam



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